

Notice of References Cited	Application/Control No. 10/054,994	Applicant(s)/Patent Under Reexamination KUSUNOKI ET AL.	
	Examiner Luke Osborne	Art Unit 2123	Page 1 of 1

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*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
	A	US-5,514,904 A	05-1996	Onga et al.	257/627
	B	US-			
	C	US-			
	D	US-			
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	I	US-			
	J	US-			
	K	US-			
	L	US-			
	M	US-			

FOREIGN PATENT DOCUMENTS

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	N					
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NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
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*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
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